

TO:

FROM:

DATE:

6 July 2003

REF:

Applicant:

Chou et al

Filing Date

15 October 2001

Serial No:

09/978,420

Att'y No.

67,200-409

Art Unit :

2815

Examiner

N Drew Richards

Title

Microelectronic Fabrication With Upper Lying Aluminum

Fuse Layer in Copper Interconnect Semiconductor Technology

and Method for Fabrication Thereof

AMENDMENT AND RESPONSE TO OFFICE ACTION

Sir:

In response to an office action mailed on 16 May 2003, please consider the following amendments and remarks pertaining to the above referenced application.

There are no amendments to the specification or the drawings. Amendments to the claims are found within the Listing of the Claims that begins on page 2 of this paper. Remarks begin on page 4 of this paper.

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to the Commissioner for Patents, POB 1450, Alexandria, WA 22313 on 2003.

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